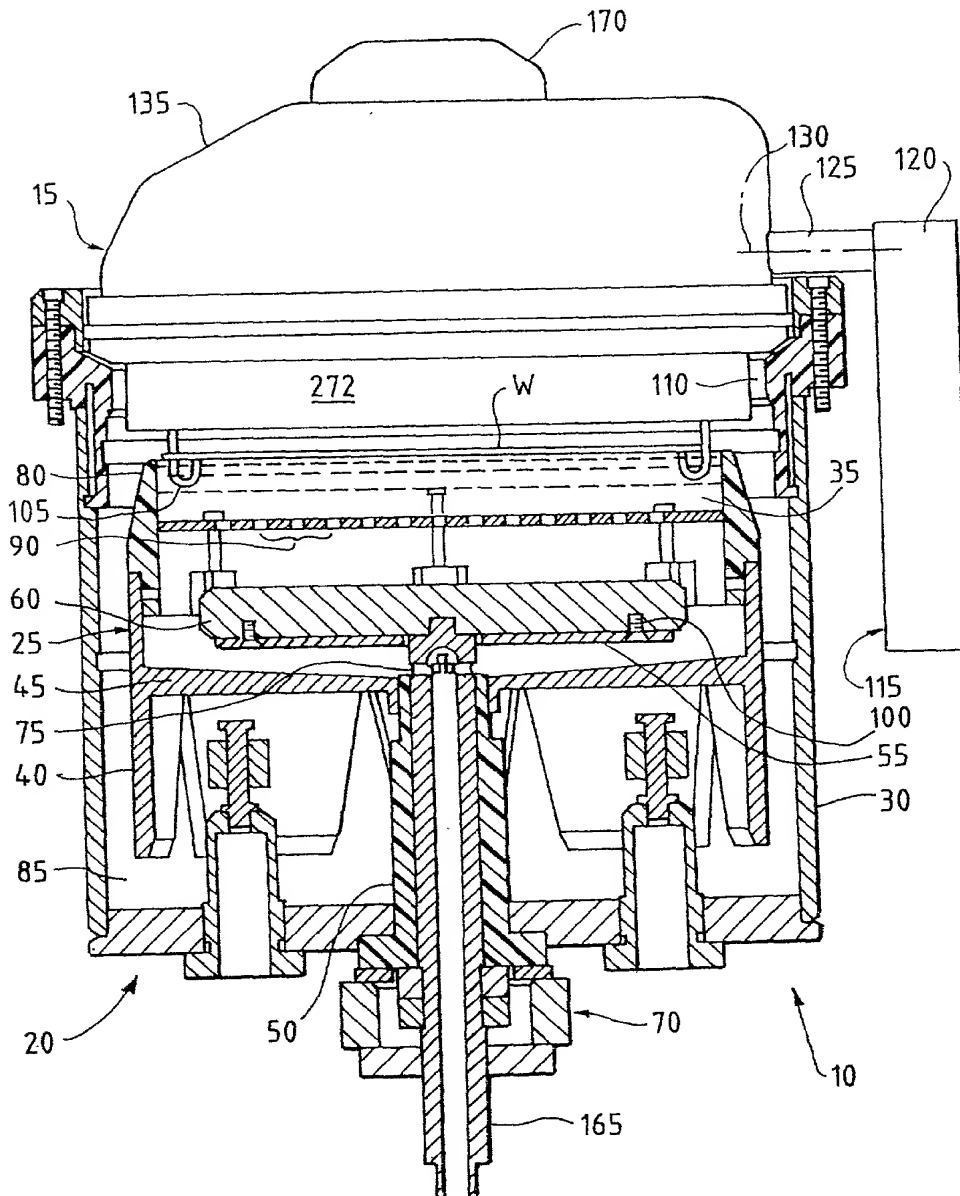


1/7

FIG. 1



2/7

FIG. 2A

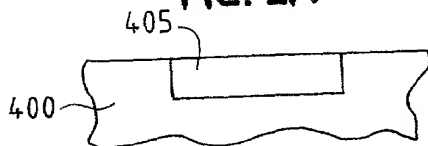


FIG. 2B

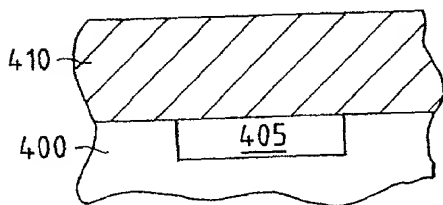


FIG. 2C

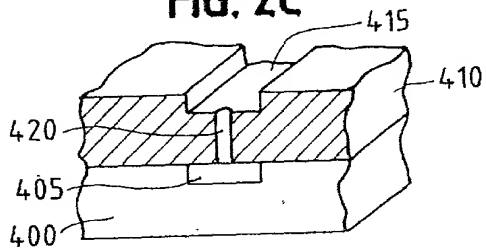


FIG. 2D

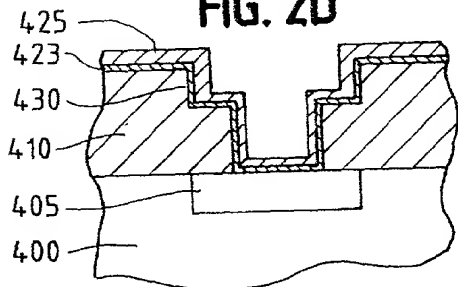


FIG. 2E

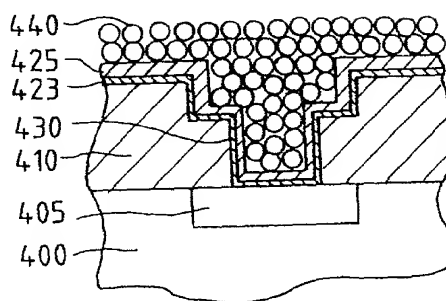


FIG. 2F

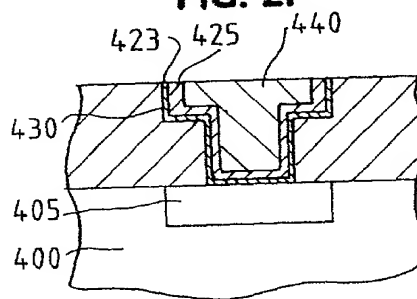
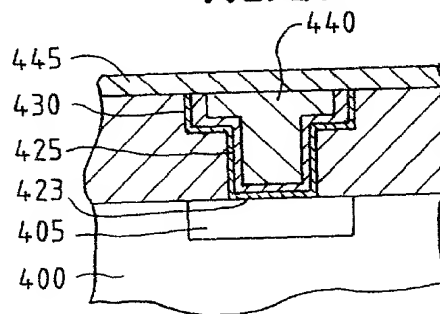


FIG. 2G



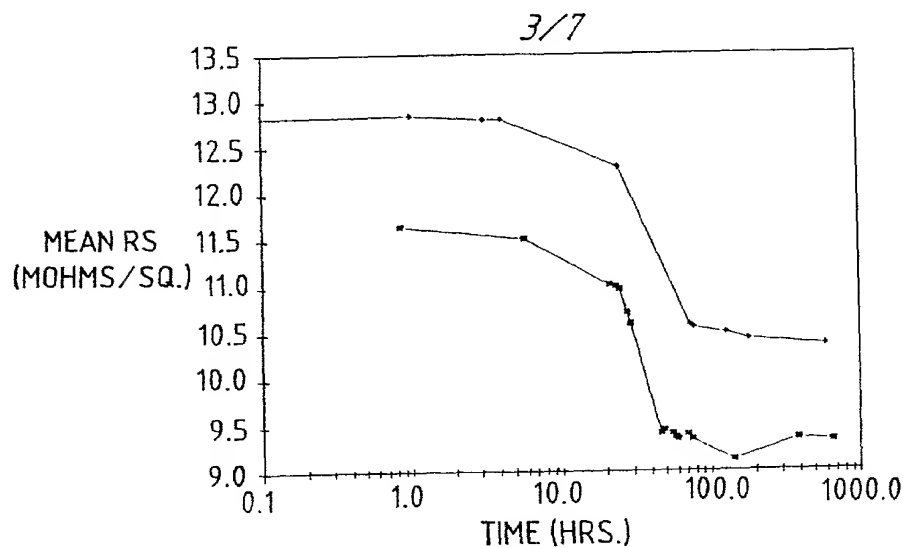


FIG. 3

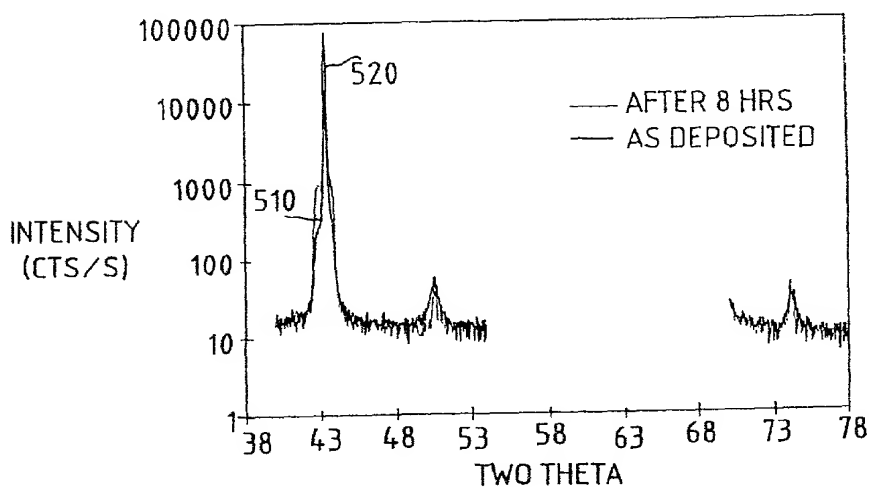


FIG. 4

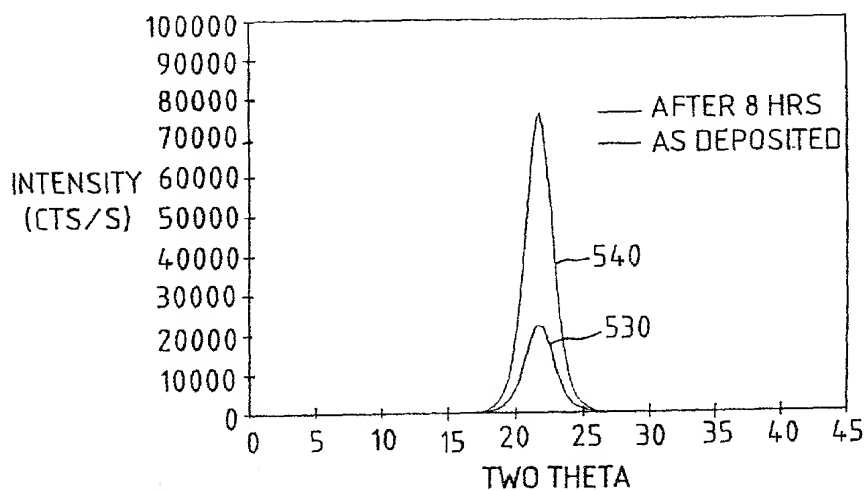


FIG. 5

4/7

FIG. 6

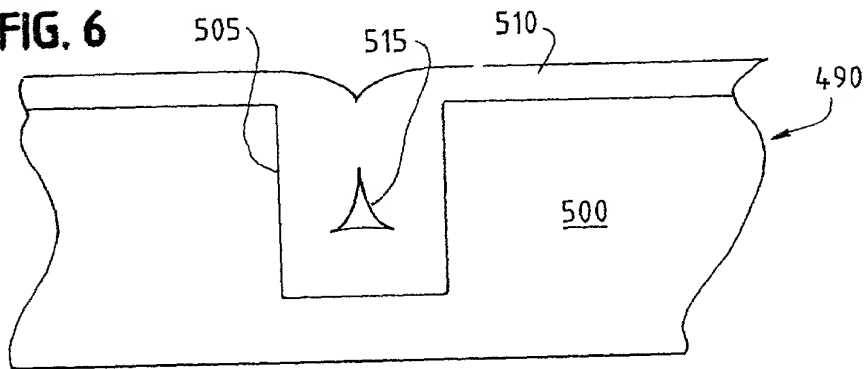


FIG. 7

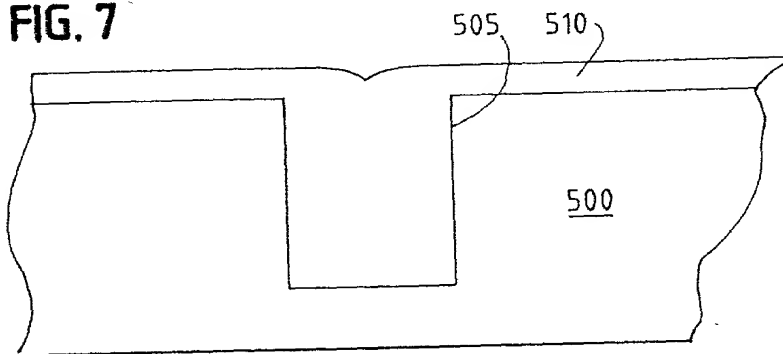
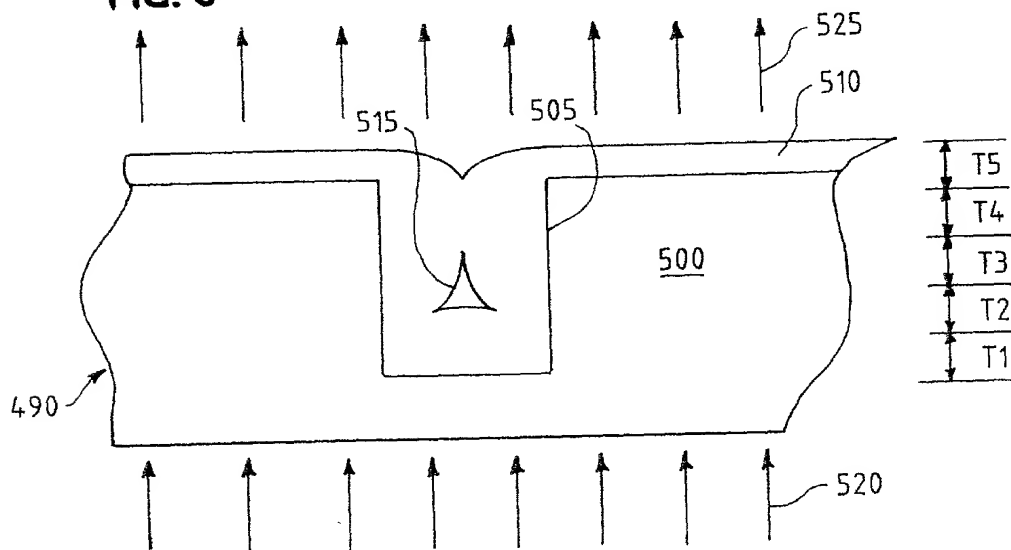


FIG. 8



5/7

FIG. 9

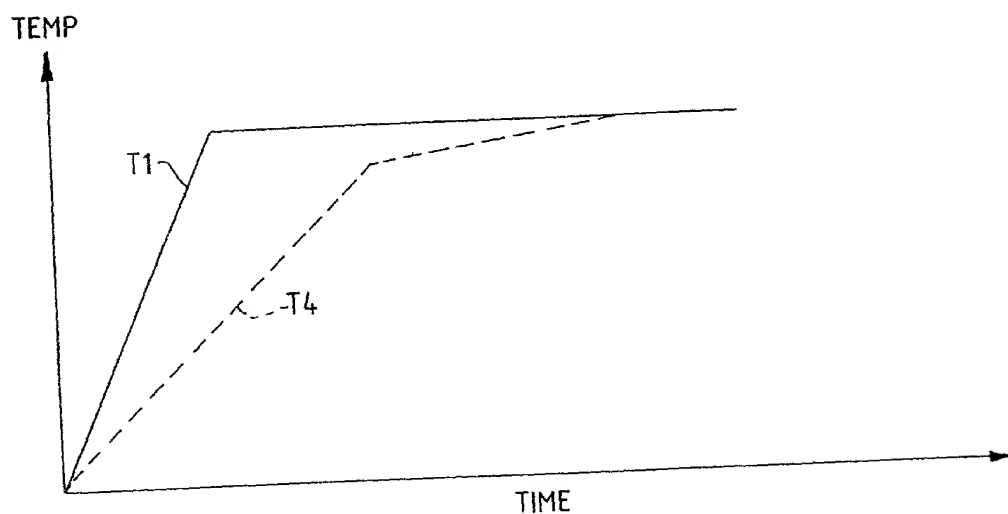
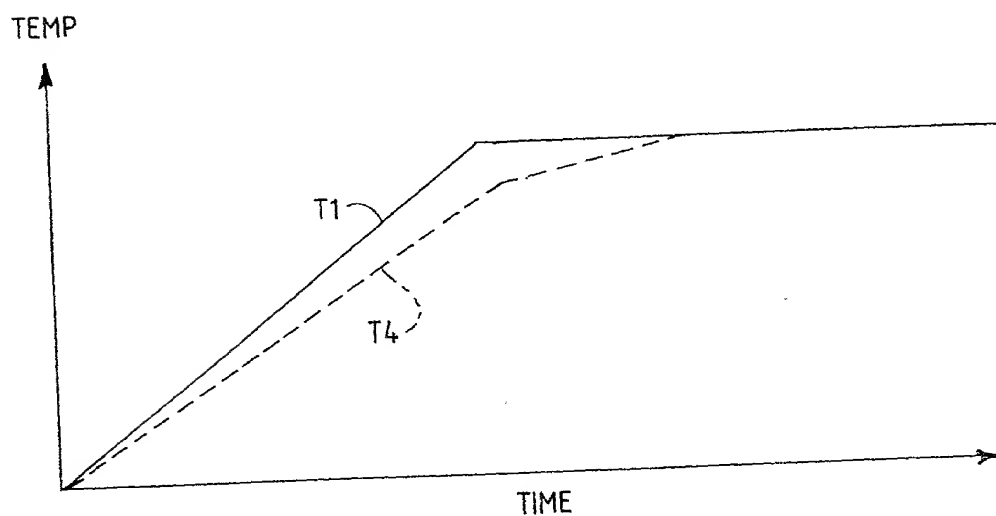


FIG. 10



Title: METHOD AND APPARATUS FOR LOW TEMPERATURE
ANNEALING OF METALLIZATION MICROSTRUCTURES IN THE
PRODUCTION OF A MICROELECTRONIC DEVICE

Inventors: T.L. Ritzdorf et al.

Docket No.: SEMT116123

6/7

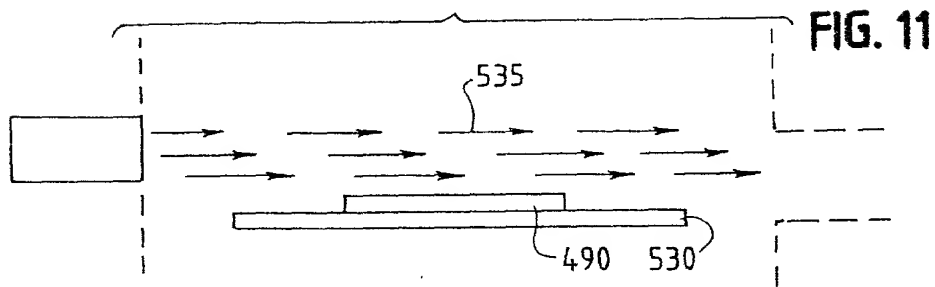


FIG. 11

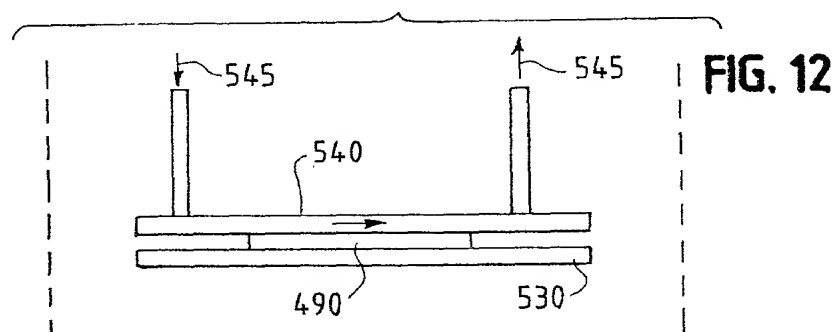


FIG. 12

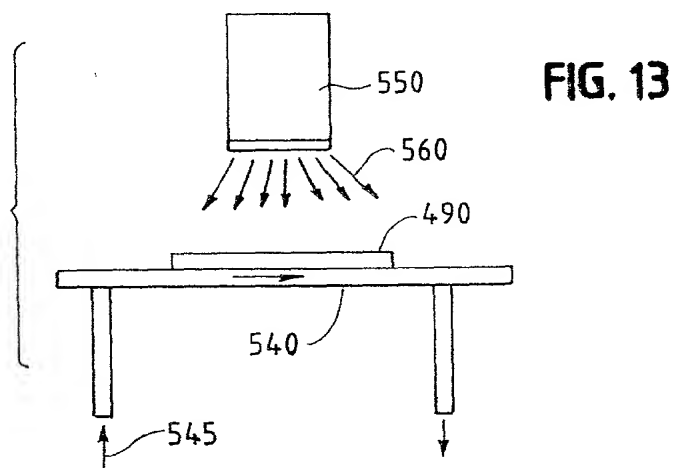


FIG. 13

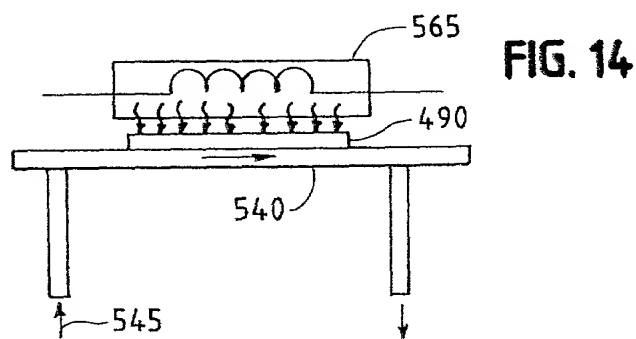


FIG. 14

T00250-512580

7/7

FIG. 15

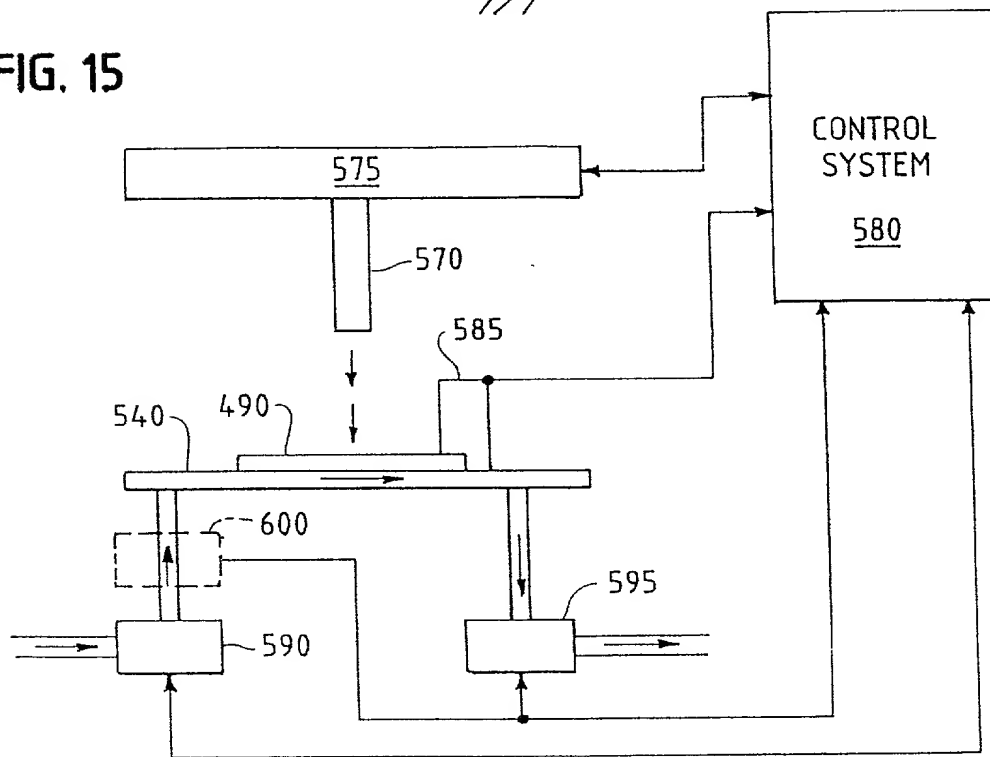


FIG. 16

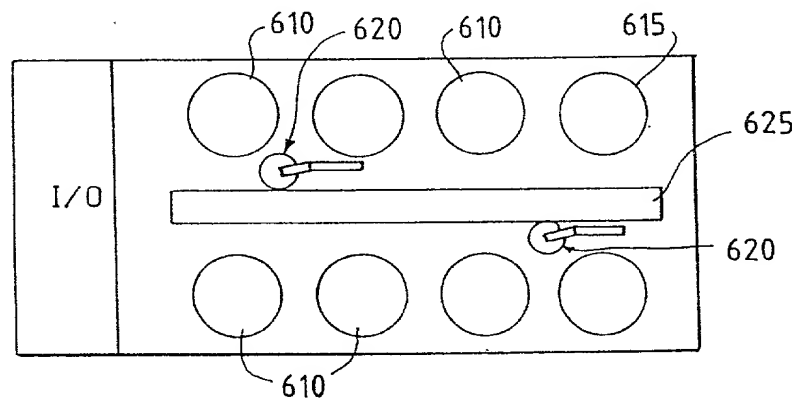


FIG. 17

